

2210-LS System Level Probe Station

Chip spins driven by the results of first-article testing of new chip designs are usually accompanied by extremely high pressure from senior management and customers to find solutions within truncated timeframes. However, application boards are typically not suitable for in-circuit e-test with traditional mechanical probing techniques. The Micromanipulator model 2210-LS application board compatible probe station has been specifically designed to assist development teams working with post tape-out product spins. Use of application boards for system level testing can significantly expedite the failure analysis operation.

The 2210-LS allows you to probe at the application board block or system level while exercising your chip in mission mode. Using the 2210-LS, you can trace and analyze issues that manifest only in the actual end application environment such as:

- Power Issues
- Inter-block device interface and tolerance issues
- Between-block issues such as Mixed-Signal Interface related Issues
- Race Condition Issues
- Clocking domain Issues

The Micromanipulator model 2210-LS probe station offers a large area, vibration isolated, open and stable platform for high magnification sample viewing and probing. Extensive application coverage is offered including basic DC, to E and K-Band analysis.

NEW ! • Application Board Thermal Test Capability*

** Patent Pending*



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2210-LS Features and Benefits

- 30" x 36" optical vibration isolation table accommodates application boards measuring approximately 26" square.
- Two independently moveable stainless steel platens accommodate up to 10 individual probe positioners. Platen movement allows for probe placement across application board area.
- Microscope coarse positioning over a 17" x 24" square area for viewing the application board without rotation. Fine controls offer increased resolution after coarse positioning.
- Standard single objective A-zoom microscope for high magnification viewing and un-obstructed probe access to sample.
- Moveable, electrically isolated application board vacuum clamping towers rigidly hold boards while accommodating boards with different thickness and XY dimensions.
- Support towers are standard to support large boards that are less rigid.
- Locking devices on platens and microscope drives offer increased stability during analysis.
- Choose manipulators, probe holders, and tips based on application requirements and personal preferences.
- Cable channels with strain relief offer easy management of cables for both application boards and probe station hardware.

Options

- Removable ambient and thermal chucks for wafer level probing needs.
- Stereo zoom and compound microscopes.
- CCD and video monitor options.
- Shroud enclosure for light shielding
- **Controlled Thermal environment: 0 - 85 deg C**, accomodates application boards up to 10 "x 10"**

** Requires separate temperature controlled forced air supply